



1764
Jfw

Certificate of Transmission Under 37 CFR1.8

I hereby certify that this correspondence is
being facsimile transmitted to the U.S. Patent
and Trademark Office (Fax. 703 872 9306) on

09/14/2004

Date

Feng Wu Niang

Name

Wu - Niang Feng

Signature

This copy is also mailed to USPTO at the same time

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant Wu-Niang Art Unit: 1764
Feng
Series No 09/944,947 Examiner: DUONG, THANH P
Filed 09-01-2001
Title Semiconductor waste-gas treating apparatus
being filth sedimentation-and
etching-proof

Mail Stop Non-Fee Amendment

Honorable Assistant Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Responsive to the Official Action date 06 / 28 / 2003, please
amend the above-referenced Patent Application as following:

AMENDMENT